

Progress on Liquid-Metal Collector Mirrors as Robust Plasma-Facing EUV & Soft X-ray Optics.

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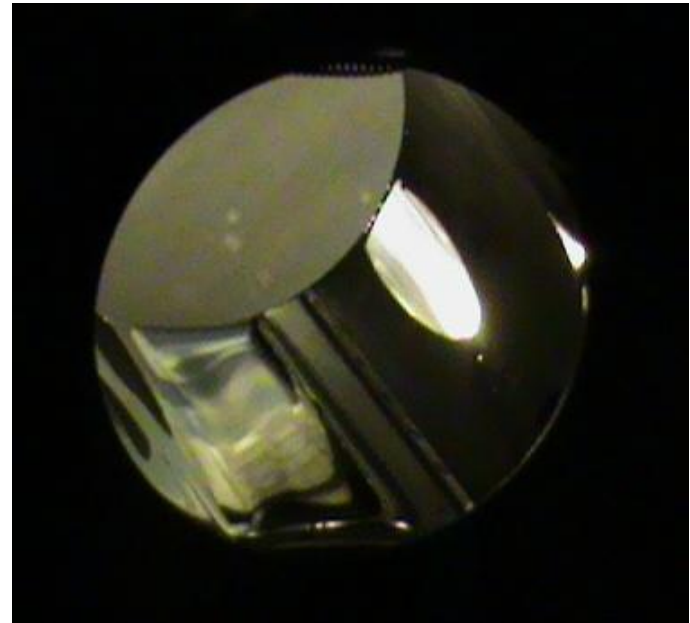


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Outline

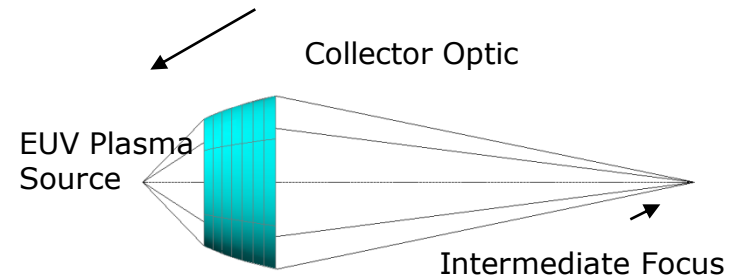
- Motivation
- The liquid metal mirrors
- Experimental setup
- The EUV sources
- Experiment & results:
 - EUV & optical
- NewLambda Technologies
- Conclusions



Motivation

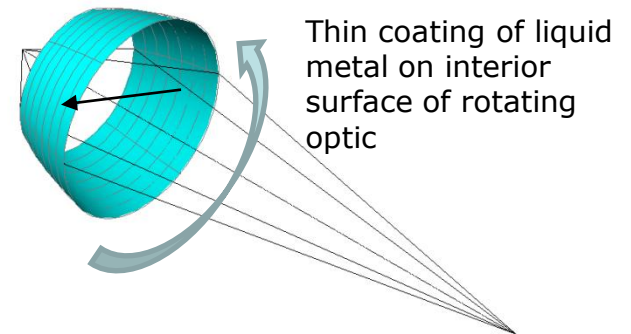
- EUV Sources for Metrology

- Simple collector
- Requires atomically flat mirror
- Sn Plasma debris + fast ions
 - Lifetime issues

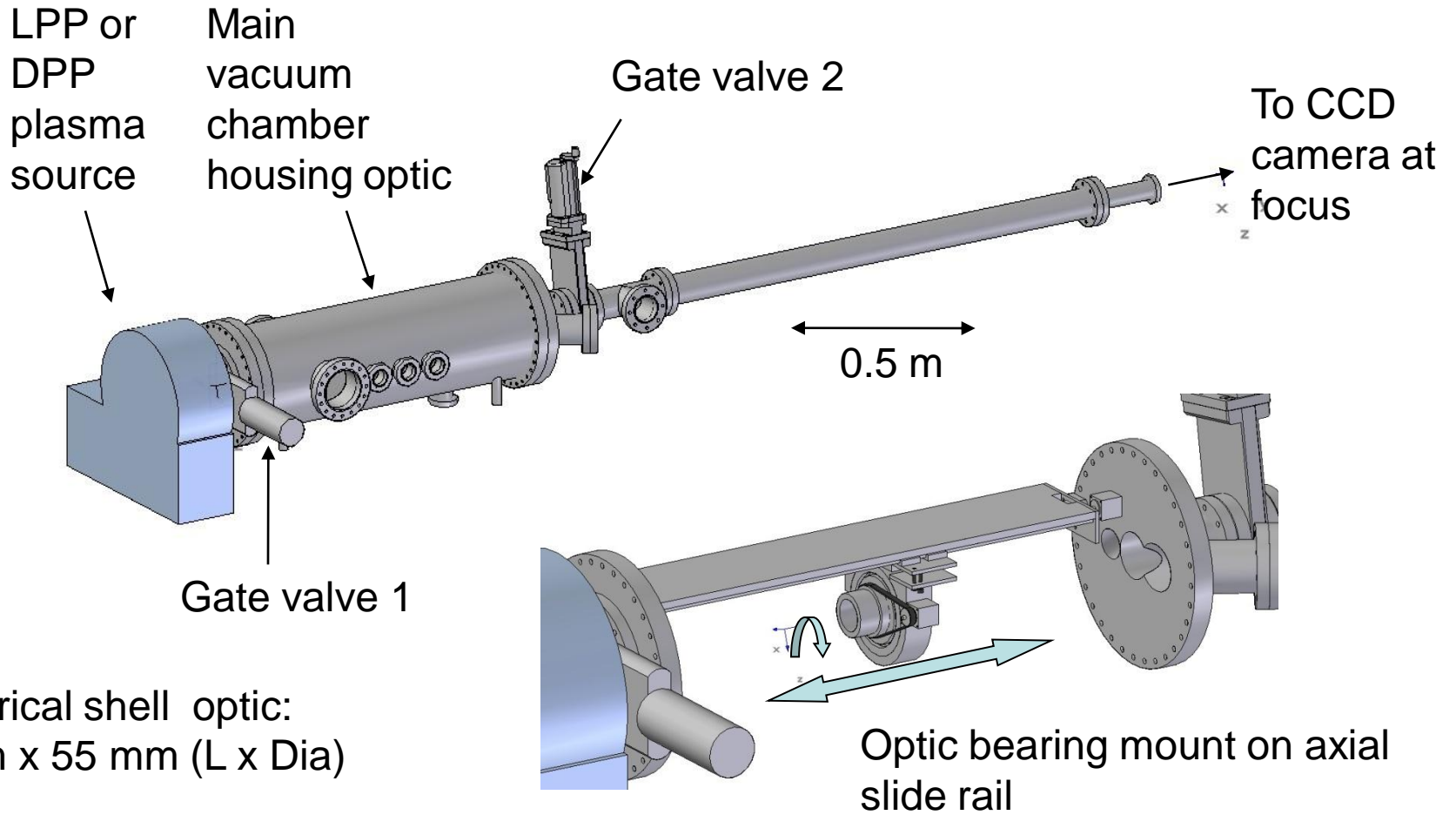


- Liquid metal coated mirror

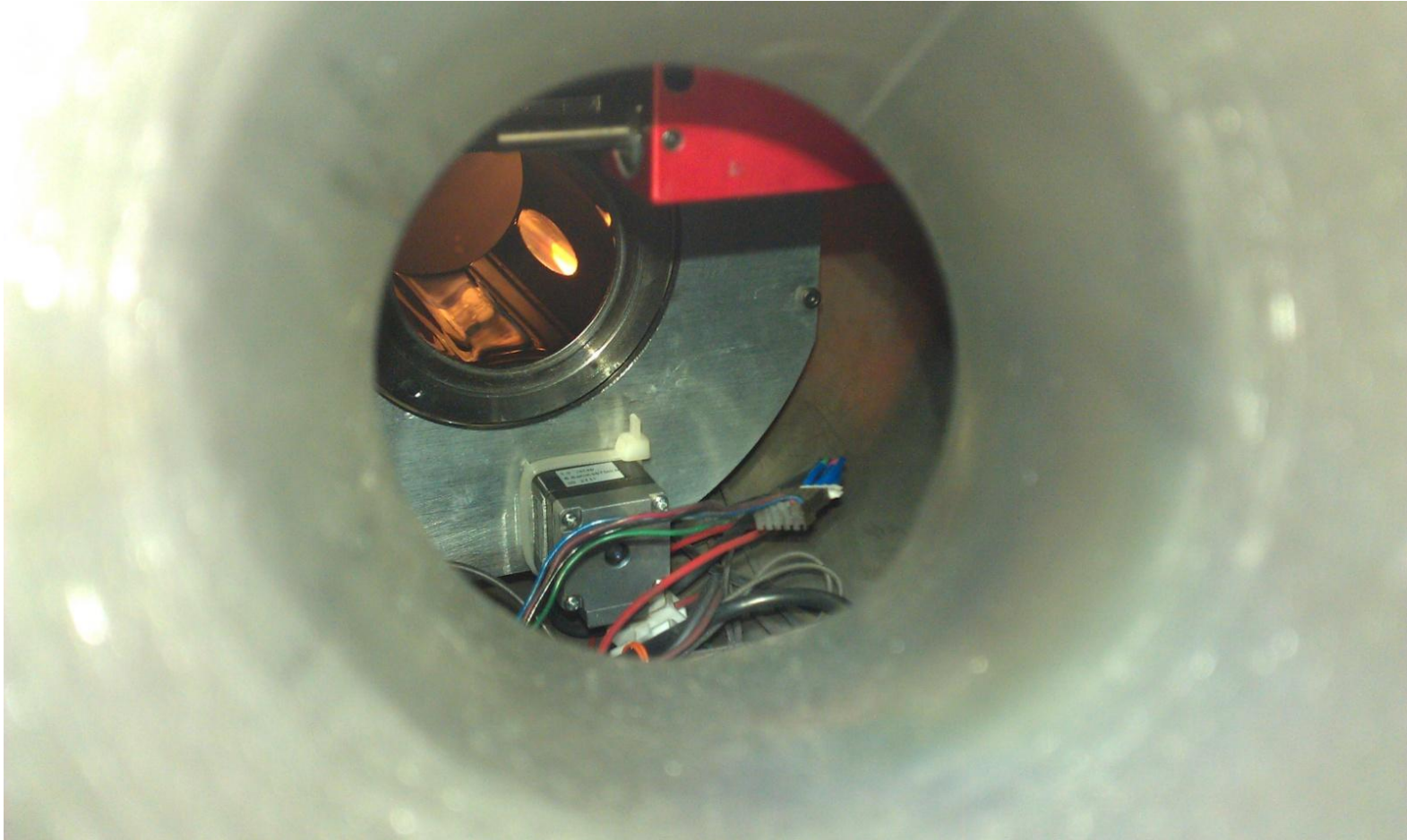
- Sn based alloy
- Relatively long lifetime
- No debris mitigation required?



Experimental Setup



The Cylindrical Mirror



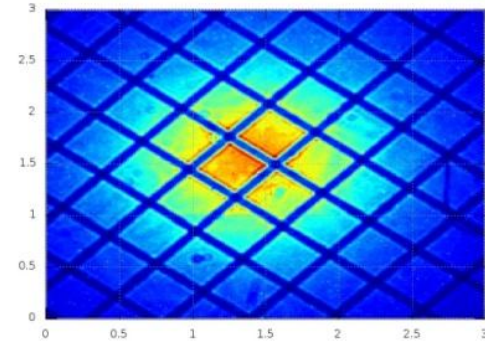
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EUV Sources

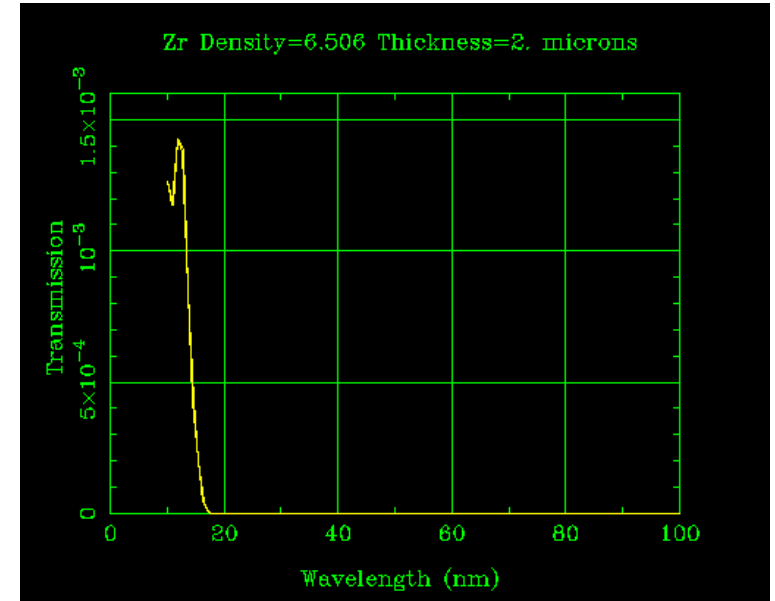
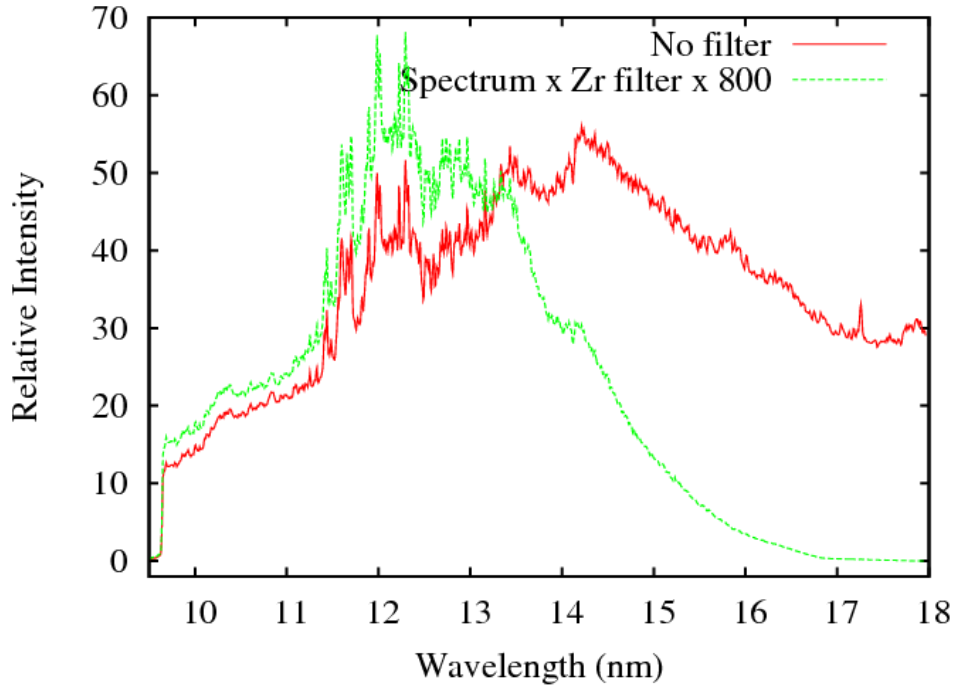
- #1 Xe, Ar DPP Bruker 200 W
- 100 Hz
- Size 300 - 500 μm

- #2 GaInSn LPP
- 50 Hz, 25 W Nd:YAG laser
- Size \sim 60 μm

- #3 Sn DPP ISAN 200 W
- 10 Hz, 50 Hz.
- Size $<$ 500 μm



EUV Spectrum - GaInSn



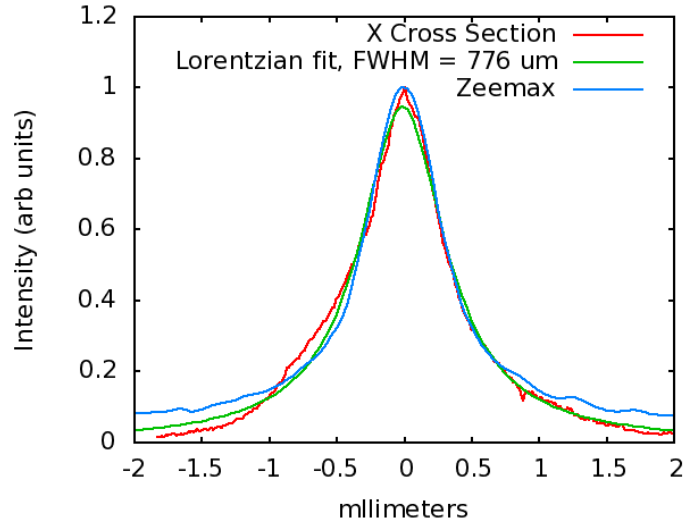
Source: CXRO



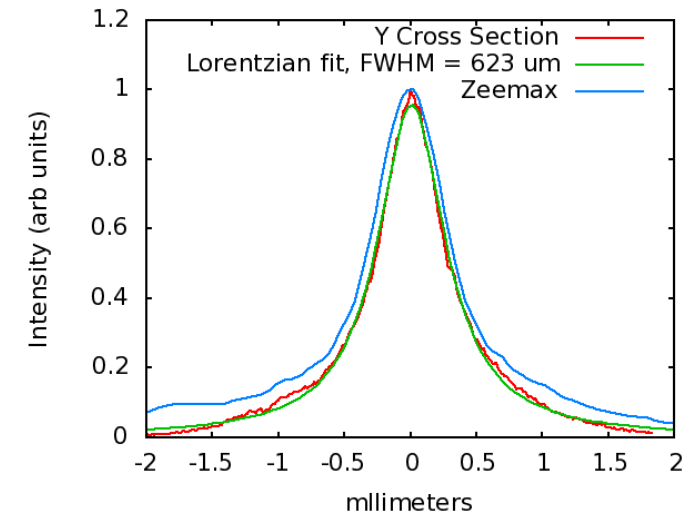
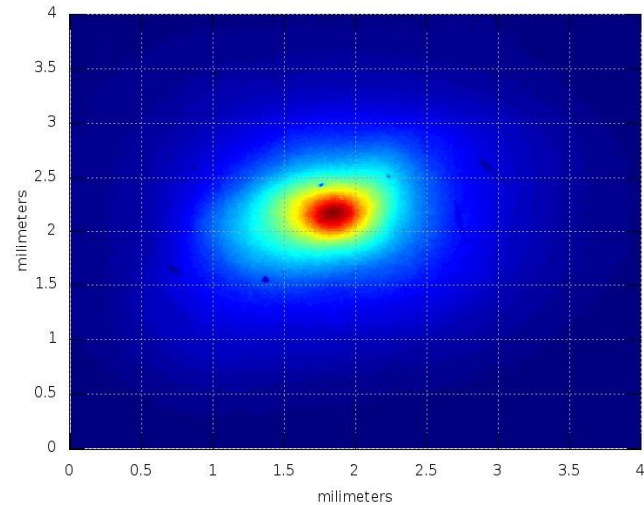
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EUV Test Data - DPP

- Bruker DPP source, Xe, 8 kV, 1.28 J, $\omega_{\text{mirror}} < 2$ r.p.m



Single shot CCD image



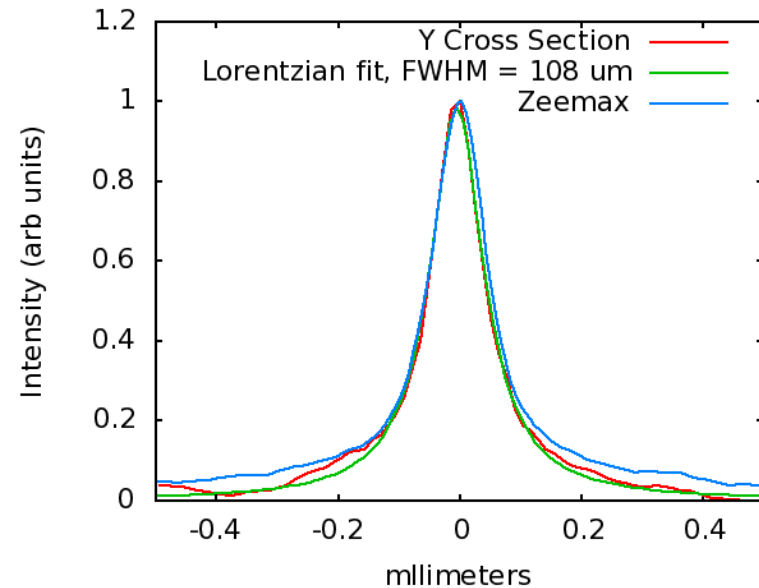
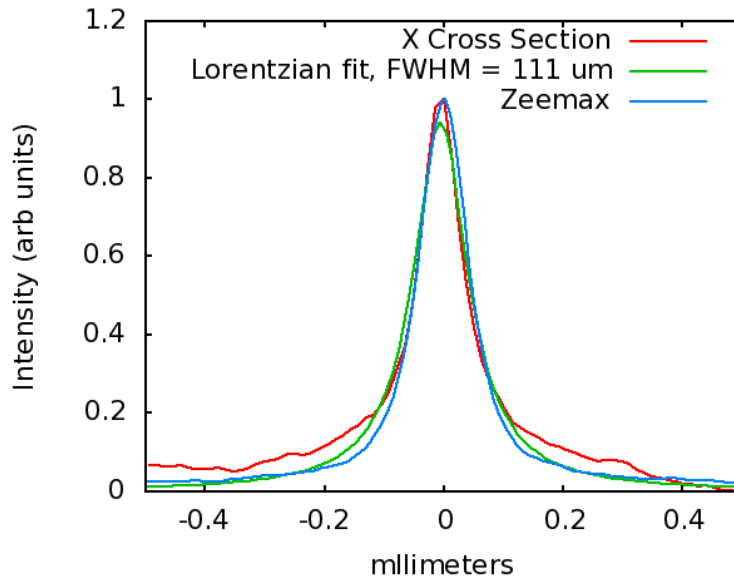
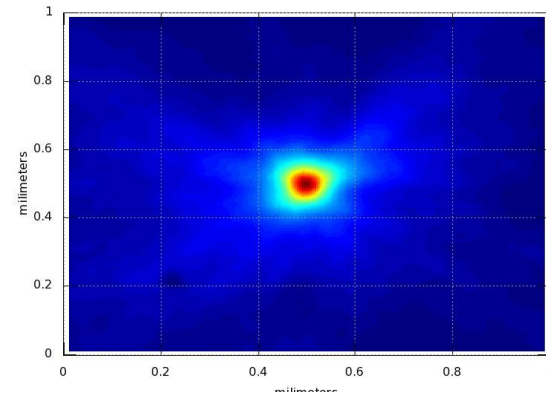
- $FWHM_x = 776 \mu\text{m}$, $FWHM_y = 623 \mu\text{m}$
- Zemax DPP source model
 - Lorentzian pinch, $FWHM = 420 \mu\text{m}$
- Asymmetry due to liquid pool – Zemax predicted



EUV Test Data - LPP

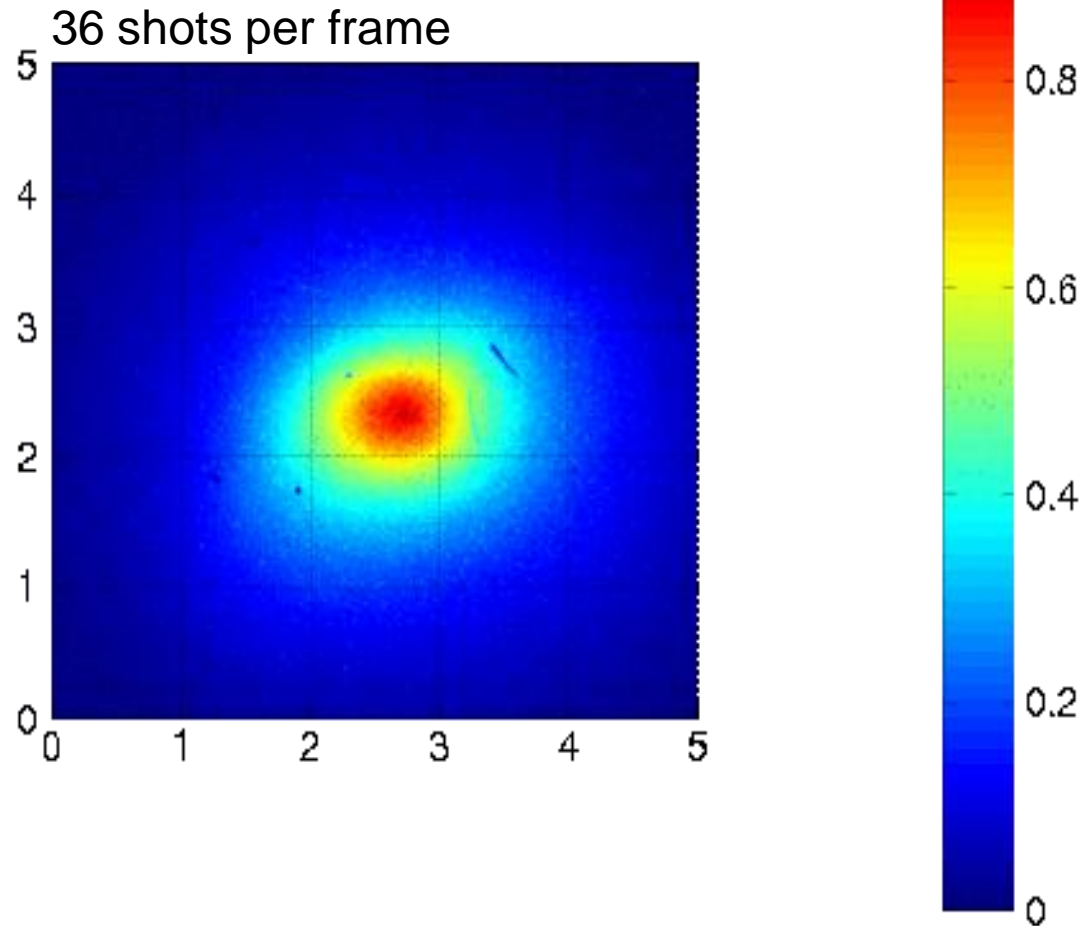
- GaInSn LPP source
- ~50 mJ on target
- Plasma size ~60 μm (Zemax)

Single shot CCD image, Zr filter 2 μm



EUV Test Data - DPP

- Rotating mirror ($\omega < 2$ r.p.m), Bruker DPP



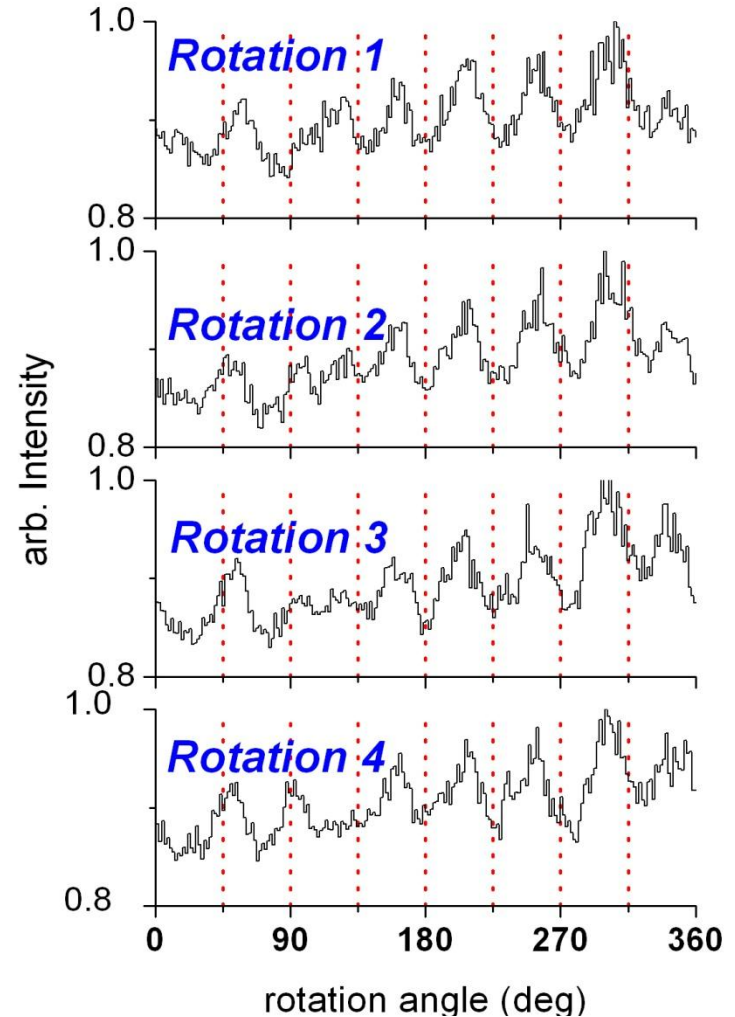
Test data – Visible

- Focused spot intensity V rotation angle
- Source FWHM = 350 μm
- $\omega_{\text{mirror}} < 2$ r.p.m
- CCD 34 f.p.s

- Fluctuations regular and repeatable over many rotations » bearing wobble

- spatial stability at focus, ± 100 μm

- Higher accuracy commercial bearings available (± 5 μm stability at focus)



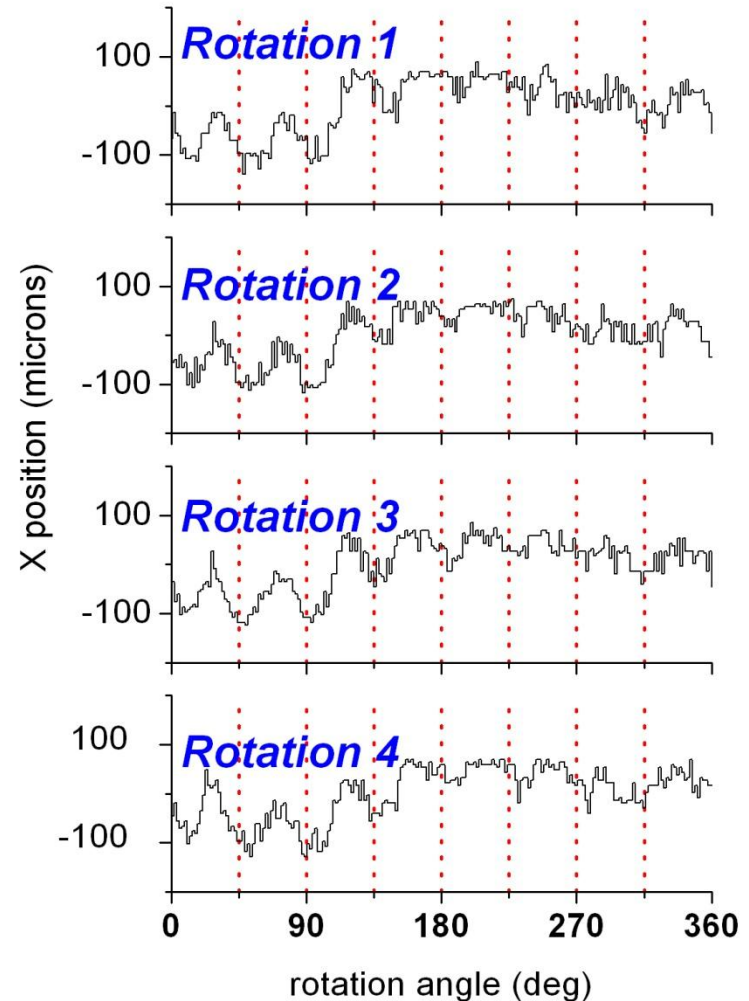
Test data – Visible

- Focused spot intensity V rotation angle
- Source FWHM = 350 μm
- $\omega_{\text{mirror}} < 2$ r.p.m
- CCD 34 f.p.s

- Fluctuations regular and repeatable over many rotations » bearing wobble

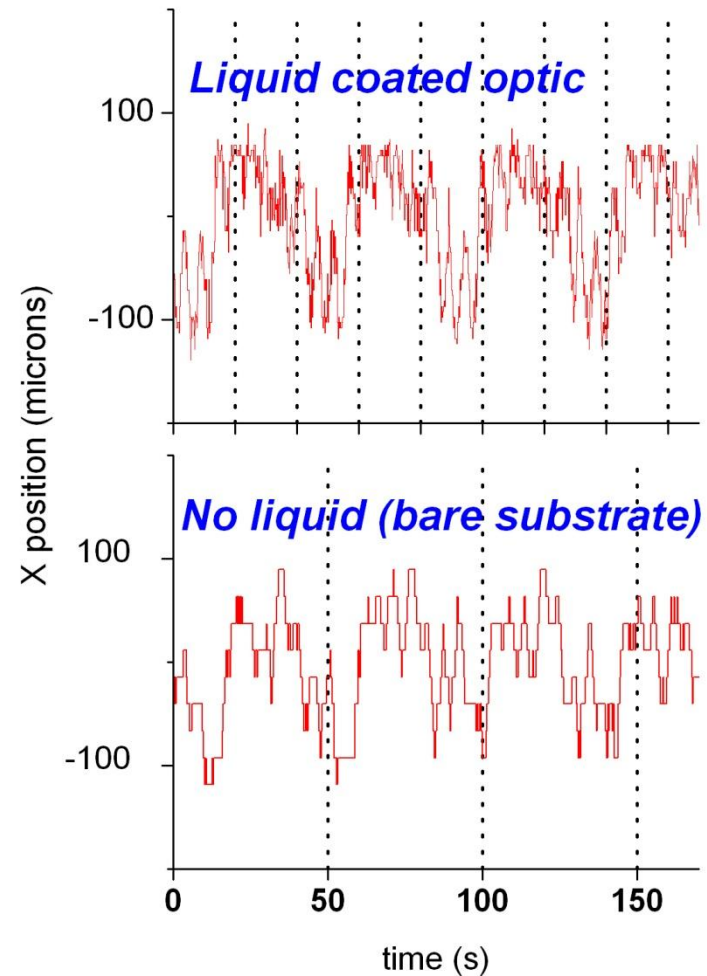
- spatial stability at focus, ± 100 μm

- Higher accuracy commercial bearings available (± 5 μm stability at focus)



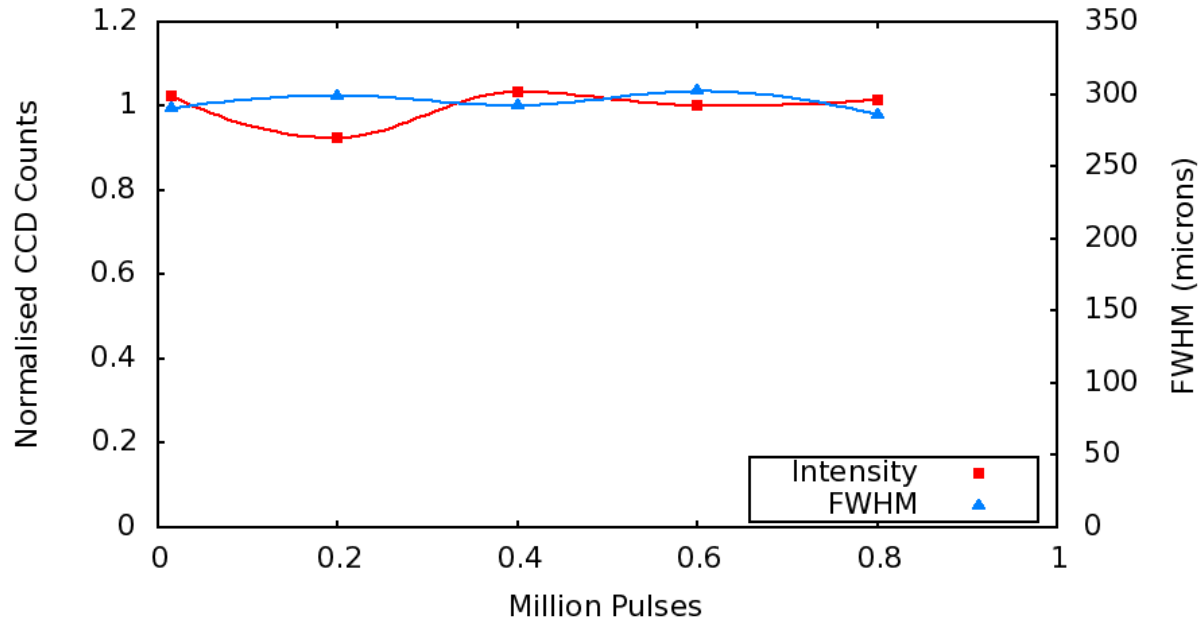
Test data – Visible

- Variations independent of liquid
- $\omega_{\text{mirror}} < 2$ r.p.m
- 34 f.p.s (coated)
- 9.7 f.p.s (uncoated)



Lifetime Data

LPP shots over 2 days – Nov 2010.



Recent activity:

- 20 million DPP shots
- Vented many times + 3 months continuous use
- Exposed to Ar, Xe, Sn & Gallinstan
- Laser irradiation of mirror surface 500mJ, 9 ns, Nd:YAG
- No obvious decrease in performance



NewLambda Technologies Ltd.

- UCD Spin Out Company
 - located on UCD campus

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Plan – next 6 months

- Improve image stability to $\pm 5 \mu\text{m}$
 - commercial bearings available
- EUV focusing from liquid coated ellipsoids
 - electroformed or diamond turned
- Image smaller & brighter sources
- Measure brightness – EUV photodiode
- Expose optic to harsh plasmas
- Engage with engineering partner to develop products
- First product prototype Sept 2011



Thank You for Listening

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